

Maximizing throughput, due date compliance and other partially conflicting objectives in semiconductor production

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https://aissi-project.com

Outline

- Overview SYSTEMA GmbH
- Use case: Epitaxy Production at Nexperia Hamburg
- Optimization Requirements
- Process Simulation
- Constraint Optimization Solver & Dispatching
- Reinforcement Learning
- Summary & Discussion



SYSTEMA

- Globally acting specialist in manufacturing business process automation and optimization
- Enable manufacturers to improve their business, delivering transparency and control with software solutions and consulting for automation & optimization
- 25+ years of experience in High Automation
- 200+ experts worldwide



SHOPFLOOR SMART CONNECTIVITY & INTEGRATION



Optimization Challenge Epitaxy Nexperia Hamburg



Use Case: Epitaxy Production at Nexperia Hamburg

- Optimize throughput and other objectives in the epitaxy area at Nexperia Hamburg
- Initial process step for majority of flow definitions
- Epi is a rate-limiting process step
- Establish analytical model to quantify production improvements and ROI
- Improvements could be better execution planning but also other types of process changes



https://www.nexperia.com/about.html



Use model-based analysis to optimize complex production processes

Assess more complex changes to production execution planning using process simulation & modelling





Optimization Criteria: Epitaxy Process

- Task Assignment Uniformity: Maximize and level tool utilization within tool group
- Minimize Set Up: Consider tool setup state when building schedule
- Shift Hand Over Overlap: Tasks should not start during a shift handover period
- Minimize Cycle Time: Schedule tasks as early as possible
- Ensure Due Date Compliance: Make sure lots are finished before their due date
- Minimize Material Transport: Consider shelf-location when scheduling lots to tools
- \rightarrow Balance conflicting production targets
- \rightarrow Complex cost function with constraints



Material Types Hold Status Material Ownership Cycle Times **Due Dates Equipment Capabilities** Anticipated Downtimes **Equipment State** Dummy/Baffle Filler Material **Tests/Experiment Conditions Date/Time Calculations** Downstream Resource State **Up/Downstream Inventory Timer Expirations Critical Ratios** Kanban **Raw Material States** Recipes **Process Times**

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Semiconductor Front End Operations



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material and methods Not always following

intuition



Simulation Model Epitaxy Area Hamburg



SYSTEMA Semiconductor Frontend Simulation Toolbox

- Discrete-event Frontend fab simulation model
- Realistic flows (cyclic routes, split/merge, rework, scrap)
- Lot & Tool granularity (with options for abstraction)
- Qualification (Stochastic, Rule-Based, Expiration)
- Tool properties (rates, load ports, batching)
- Flexible statistic and rule-based lot release
- Tool down, maintenance, personnel
- "Warm start" using material & tool state data
- Fast: simulate **a year** of production **in just seconds**





Maximizing Conflicting Objectives in Semiconductor Production

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Modelling & Simulation Toolbox: Core Features

- <u>kalasim</u> Fast generic process-oriented discrete event simulation engine
- Simulation entities have a generative process descriptions that define the interplay with other entities
- Rich process interaction vocabulary
- Built-in monitoring and statistics gathering across the entire toolbox
- MIT License, hosted at <u>github</u>, documentation & examples <u>https://www.kalasim.org</u>





Epitaxy Process Simulation

Parametrized using various data snapshots from MES, ERP and maintenance planning



Maximizing Conflicting Objectives in Semiconductor Production

Art of Automation

Epitaxy Process Simulation: Tool State & Setup

Area throughput limited by multiple resources (lot provisioning, operators, tools, maintenance)





Maximizing Conflicting Objectives in Semiconductor Production

Epitaxy Process Simulation: Operators



Operator Activities excluding Idle Times





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Maintenance Planning

- Maintenance tasks are defined in external ERP system
- Tools loose qual if maintenance does not happen within defined time window





Simulation-enabled **Production Optimization**



Optimize Bottleneck Tool Groups by Reducing Standby

- "Standby" status very present in all reference tool groups
- Multifactorial problem





How much throughput could be gained with a simpler operator interface?

- Fewer degrees of freedom
- Less information





Operator Workload in Epitaxy Area

- Understaffed area: waiting for qual and operators are a major productivity constraint
- Detailed area model including operator activities
- ~5min spent to select next lot and to track it into MES
- What if we could streamline the operator guidance process to save just these five minutes?





Improved Operator Guidance and Interface \rightarrow +5% Throughput

Considered two simulation scenarios

- Classic it takes 5 mins to select and track-in a lot
- Streamlined it takes a negligible time to do so
- 14 days (with repetition)
- Significant productivity boost from better operator guidance
- Improved productivity in bottleneck areas



Art of Automatio

SYSTEMA Event-Driven Dispatcher

Optimize production with rules & heuristics

Capabilities and rules configured by Engineers

- Generate equipment specific dispatching lists
- Uses Planning / Scheduling Information
- Engineers directly configure the system

Effective setup and monitoring by Line Control

- Rules for configuring Fab Optimization Criteria
- Bottleneck management
- Real-time monitoring and control

Efficient use by Operators

- Including all required information at one glance
- Look ahead, batching, timers





SYSTEMA Shopfloor Scheduler

- Al constraint solver
- Based on lightweight, embeddable planning engine
- Extensions for 4M semi-production optimization (Staffing, Material, Routes)
- Over-constrained planning
- Continuous, event-driven planning
- Planning entity pinning
- Multi-stage planning





Planning Method Performance Analysis

Scheduler outperforms baseline dispatching rules









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Reinforcement Learning Enabled Shopfloor Execution Planning

- RL learns complex system mechanics/dynamics from exploration and correlation and can generalize these information to new situations
- Part of ongoing governmental funded research collaboration AISSI <u>http://aissi-project.com</u>
- Extended model proposed in:

Tassel, Pierre, Martin Gebser, and Konstantin Schekotihin. "A reinforcement learning environment for job-shop scheduling." *arXiv preprint arXiv:2104.03760* (2021)





Extended RL model with due-date and shift-handover

- Operators need to hand over area to next shift
- During shift-handover, new lots won't be started since operators are busy







RL Results & Discussion - Many remaining challenges

- Only assessed very small WIP configuration
- Poor generalization
- Not all optimization requirements of Nexperia could be modelled with the RL agent
- Suitable problem formulation
- MCTS compute requirements
- Unclear AI Ops Process & Roles



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Maximizing throughput, due date compliance & other partially conflicting objectives in semiconductor production

- 1. Start simple with rule-based optimization
 - → Event-Driven Dispatcher
- 2. Establish analytical process
 → Process Analytics & Consulting
- Improve execution planning with scheduling to further optimize production
 → SYSTEMA Scheduler



